



Mgr. Michal Štipl

Patent Specialist

PatentEnter

Michal Štipl started his career as a **Patent Specialist** in 2017 **during his university studies at Masaryk University**, where he studied **Applied Physics and Plasma Physics**. In his bachelor thesis he researched quality of hydrophilic thin films created in plasma, during his master's studies he focused on fundamental research and studied properties and mobility of barrier discharges. Michal is **co-author of several articles** published in various scientific journals concerning **thin films and plasma physics**.

After graduating in 2019, Michal became a full-time employee in the company **PatentEnter** where he **performs searches for patentability and freedom to operate**. He also **drafts patent applications in cooperation with researchers and developers** from various companies and institutes, including **Czech Academy of Sciences, Brno University of Technology, Palacky University, University of Hradec Kralove, Tescan Brno**, manufacturer of electron microscopes, and many others.

As a physicist, he mainly occupies himself with inventions concerning laboratory equipment, electron microscopes, and more recently software inventions and software patents, as they are forming an increasing number of patent applications filed worldwide and present an interesting and challenging area for patent attorneys.